

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1752		Priority SERIAL NO. 09/652,532	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Garo J. Derderian			
				Priority FILING DATE August 31, 2000		Priority GROUP 28 <u>22</u>	
U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
TMT	AA	09/653,149	Derderian	—	—	08/31/00	
11	AB	09/653,156	Agarwal	—	—	08/31/00	
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
	AM						
	AN						
	AO						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
TMT	AP		A.W. Ott, et al., "Atomic layer controlled deposition of Al ₂ O ₃ films using binary reaction sequence chemistry" Applied Surface Science (107) 1996, pps. 128-136.				
	AO						
	AR						
EXAMINER			DATE CONSIDERED				
T.M. Thomas			12-23-02				
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

 JCS97 U.S. PTO
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